

New PCT National Phase Application

Docket No. 2691-000013/US

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## IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant(s): Kohshi TAGUCHI and Masahiro YOSHIMOTO  
Int'l App. No.: PCT/JP2003/008552  
Application No.: **NEW APPLICATION**  
Filed: January 7, 2005  
For: METHOD AND APPARATUS FOR FORMING  
NITRIDED SILICON FILM

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**PRELIMINARY AMENDMENT**

U.S. Patent and Trademark Office  
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Customer Window – Mail Stop PCT  
Crystal Plaza Two, Lobby, Room 1B03  
Arlington, VA 22202

January 7, 2005

Sir:

The following preliminary amendments and remarks are respectfully submitted in connection with the above-identified application. Prior to examination of the present application, please consider the following:

**Amendments to the Claims** begin on page 2 of this Preliminary Amendment.